

213345US-2 CONT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF: :
Kane fumi NAKAHARA ET AL. : EXAMINER:
SERIAL NO.: NEW APPLICATION :
FILED: HEREWITH : GROUP ART UNIT:
FOR: EXPOSURE APPARATUS, LITHOGRAPHY
SYSTEM AND CONVEYING METHOD,
AND DEVICE MANUFACTURING METHOD
AND DEVICE

PRELIMINARY AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

Prior to examination on the merits, please amend this application as follows:

IN THE SPECIFICATION

Please amend the specification as shown in the marked-up copy following this amendment.

Please replace the paragraph beginning on page 1, lines 7-11, with the following:

CROSS REFERENCE TO RELATED APPLICATION

This is a continuation of International Application PCT/JP00/01075, with an international filing date of February 25, 2000, the entire content of which being hereby incorporated herein by reference, which was not published in English.

Consequently, an action on the merits is earnestly solicited.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



22850

Tel. (703) 413-3000
Fax. (703) 413-2220
(OSMMN 11/98)

A handwritten signature in black ink, appearing to read 'J. Maier', written over the printed name.

Gregory J. Maier
Attorney of Record
Registration No. 25,599

James D. Hamilton
Registration No. 28,421

213345US-2 CONT

Marked-Up Copy
Serial No: <u>New App</u>
Amendment Filed on: <u>8-24-01</u>

IN THE SPECIFICATION

Please replace the paragraph beginning on page 1, lines 7-11, with the following:

CROSS REFERENCE TO RELATED APPLICATION

This is a continuation of International Application PCT/JP00/01075, with an international filing date of February 25, 2000, the entire content of which being hereby incorporated herein by reference[.], which was not published in English.